Application No. Filing Date Examiner 10/779,904-Conf. #9608 February 17, 2004 Not Yet Assigned Applicant(s): Masahiro Ishida et al. Invention: METHOD AND APPARATUS FOR DEFECT ANALYSIS OF SEMICONDUCTIVE TO THE COMMISSIONER FOR PATENTS Transmitted herewith is an amendment in the above-identified application. The fee has been calculated and is transmitted as shown below.	Art Unit 2136
Applicant(s): Masahiro Ishida et al. Invention: METHOD AND APPARATUS FOR DEFECT ANALYSIS OF SEMICONDUCTION INTEGRATED CIRCUIT TO THE COMMISSIONER FOR PATENTS Transmitted herewith is an amendment in the above-identified application.	
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Parameter	
CLAIMS AS AMENDED Claims Highest	
Remaining Number Number After Previously Extra Claims Amendment Paid Present Rate	
Total Claims 0 - 20 = 0 x 50.00	0.00
Independent 3 - 3 = 0 x 210.00	0.00
Multiple Dependent Claims (check if applicable)	
Other fee (please specify):	0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:	0.00
x Large Entity Small Entity	
x No additional fee is required for this amendment.	
Please charge Deposit Account No in the amount of \$ A duplicate copy of this sheet is enclosed.	<u></u> •
A check in the amount of \$ to cover the filing fee is enclosed.	
Payment by credit card. Form PTO-2038 is attached.	
The Director is hereby authorized to charge and credit Deposit Account No5 as described below. A duplicate copy of this sheet is enclosed.	50-0591
x Credit any overpayment.	
x Charge any additional filing or application processing fees required under 37 CFR 1	1.16 and 1.17.
Dated: November	er 26, 2007
Thomas K. Scherer Attorney/Agent Reg. No.: 45,079	
OSHA LIANG LLP 1221 McKinney St., Suite 2800 Houston, Texas 77010 (713) 228-8600	